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U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No.[1]	U.S. Patent Document Number	Kind Code[2] (if known)	Name of Patentee or Applicant Of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
KBA	A1	4,731,670		Allen et al.	03-15-1988	
	B1	4,805,038		Seligson	02-14-1989	
	C1	5,115,344		Jaskie	05-19-1992	
	D1	5,202,785		Nelson	04-13-1993	
	E1	5,206,557		Bobbio	04-27-1993	
	F1	5,212,582		Nelson	05-18-1993	
	G1	5,233,456		Nelson	08-03-1993	
	H1	5,392,151		Nelson	02-21-1995	
	I1	5,396,066		Ikeda et al.	03-07-1995	
	J1	5,781,670		Deacon et al.	07-14-1998	
	K1	5,794,023		Hobbs et al.	08-11-1998	
	L1	5,836,203		Martin et al.	11-17-1998	
	M1	5,841,579		Bloom et al.	11-24-1998	
	N1	5,847,859		Murata	12-08-1998	
	O1	5,870,221		Goossen	02-09-1999	
	P1	5,905,589		Tanaka et al.	05-18-1999	
	Q1	5,920,418		Shiono et al.	07-06-1999	
	R1	5,953,161		Troxell et al.	09-14-1999	
	S1	5,991,079		Furlani et al.	11-23-1999	
	T1	5,998,906		Jerman et al.	12-07-1999	
KB	U1	6,004,912		Gudeman	12-21-1999	

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Examiner Initials*	Cite No.[1]	Foreign Patent Document Office[3]	Number[4]	Kind Code[5] (if known)	Name of Patentee or Applicant Of Cited Document	Date of Publication of Cited Document MM-DD-YYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T[6]

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U.S. PATENT DOCUMENTS

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[illegible]	A2	6,014,257		Furlani et al.	01-11-2000	
	B2	6,031,652		Furlani et al.	02-29-2000	
	C2	6,038,057		Brazas, Jr. et al.	03-14-2000	
	D2	6,061,166		Furlani et al.	05-09-2000	
	E2	6,067,183		Furlani et al.	05-23-2000	
	F2	6,088,148		Furlani et al.	07-11-2000	
	G2	6,072,620		Shiono et al.	06-06-2000	
	H2	6,108,117		Furlani et al.	08-22-2000	
	I2	6,130,770		Bloom	10-10-2000	
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	K2	6,144,481		Kowarz et al.	11-07-2000	
	L2	6,169,624	B1	Godil et al.	01-02-2001	
	M2	6,175,443	B1	Aksyuk et al.	01-16-2001	
	N2	6,188,519	B1	Johnson	02-13-2001	
	O2	6,215,579	B1	Bloom et al.	04-10-2001	
	P2	6,233,087	B1	Hawkins et al.	05-15-2001	
	Q2	6,238,581	B1	Hawkins et al.	05-29-2001	
	R2	6,243,194	B1	Brazas, Jr. et al.	06-05-2001	
	S2	6,252,697	B1	Hawkins et al.	06-26-2001	
	T2	6,268,952	B1	Godil et al.	07-31-2001	
[illegible]	U2	6,282,012	B1	Kowarz et al.	08-28-2001	

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	A3	6,172,796	B1	Kowarz et al.	01-09-2001	
	B3	6,282,213	B1	Gutin et al.	08-28-2001	
	C3	6,284,560	B1	Jech, Jr. et al.	09-04-2001	
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	G3	5,022,745		Zayhowski et al.	06-11-1991	
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	J3	5,175,521		Larson	12-29-1992	
	K3	5,291,502		Pezeshki et al.	03-01-1994	
	L3	5,311,360		Bloom et al.	05-10-1994	
	M3	5,353,641		Tang	11-11-1994	
	N3	5,561,523		Blomberg et al.	11-01-1996	
	O3	5,629,951		Changj-Hasnain et al.	05-13-1997	
	P3	5,640,133		MacDonald et al.	06-17-1997	
	Q3	5,646,772		Yurke	07-08-1997	
	R3	5,654,819		Goossen et al.	08-05-1997	
	S3	5,661,592		Bornstein et al.	08-26-1997	
	T3	5,696,662		Bauhahn	12-09-1997	
	U3	5,757,536		Ricco et al.	05-26-1998	

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	A4	5,905,571		Butler et al.	05-18-1999	
	B4	5,739,945		Tayegati	04-14-1998	
	C4	5,966,235		Walker	10-12-1999	
	D4	5,978,127		Berg	11-02-1999	
	E4	5,999,319		Castracane	12-07-1999	
	F4	5,933,277		Troxell et al.	08-03-1999	
	G4	5,949,568		Koo et al.	09-07-1999	
	H4	5,969,848		Lee et al.	10-19-1999	
	I4	6,181,458		Brazasm Hr, et ak,	01-30-2001	

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Examiner Initials*	Cite No.[1]	Foreign Patent Document Office[3]	Number[4]	Kind Code[5] (if known)	Name of Patentee or Applicant Of Cited Document	Date of Publication of Cited Document MM-DD-YYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T[6]

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OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.[1]	Included name of the author (in CAPITAL LETTERS). Title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T[2]
KBA	A5	FURLANI et al., "Analysis of grating light valves with partial surface electrodes," *J. Appl. Phys.*, Vol. 83, No. 2, pp. 629-634, January 15, 1998.	
	B5	HUNG, "Positioning, Control, and Dynamics of Electrostatic Actuators for Use in Optical and RF Systems, Ph.D. Thesis, Massachusetts Institute of Technology, August 21, 1998.	
	C5	JERMAN et al., "Miniature Fabry-Perot Interferometers Micromachined in Silicon for use in Optical Fiber WDM Systems, *IEEE 1991 Int. Conf. On Solid-State Sensors and Actuators, Digest of Technical Papers*, pp. 372, 375, 1991.	
	D5	PETERSEN, "Micromechanical light modulator array fabricated on silicon," *Appl. Phys. Lett.*, Vol. 31, No. 8, pp. 521-523, October 1977.	
	E5	HUNG et al., "Leveraged Bending for Full-Gap Positioning With Electrostatic Actuation," *Solid State Sensor and Actuator Workshop,* Hilton Head, SC, Digest, pp. 83-86, June 8-11, 1998.	
	F5	BIFANO et al., "MEMs Deformable Mirrors for Adaptive Optics," *Solid State Sensor and Actuator Workshop*, Hilton Head, SC, Digest, pp. 71-74, June 8-11, 1988.	
	G5	SOLGAARD et al., "Deformable grating optical modulator," *Optics Letters*, Vol. 17, No. 9, pp. 688-690, May 1992.	
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	J5	HOM, Simulating electrostrictive deformable mirrors II. Nonlinear dynamic analysis," *Smart Mater. Struct.*, Vol. 8, pp. 700-708, 1999.	
	K5	MALI et al., "Development of microelectromechanical deformable mirrors for phase modulation of light," *Optical Eng.*, Vol. 36, No. 2, pp. 542-548, February 1997.	
	L5	COWEN et al., "Optical phase modulation using a refractive lenslet array and microelectromechanical deformable mirror," *Optical Eng.*, Vol. 37, No. 12, pp. 3237-3247, December 1998.	
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KBA	N5	HORENSTEIN et al., "Real time optical correction using electrostatically actuated MEMs devices," *Journal of Electrostatics*, Vol. 46, pp. 91-101, 1999.	

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OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS			
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KBA	A6	COWAN et al., "Surface Micromachined Segmented Mirrors for Adaptive Optics," *IEEE Jnl. Of Selected Topics in Quantum Electronics*, Vol. 5, No. 1, pp. 90-101, January/February 1999.	
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	E6	GANI et al., "Variable gratings for optical switching: rigorous electromagnetic simulation and design," *Optical Engineering*, Vol. 38, No. 3, pp. 552-557, March 1999.	
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	I6	BURNS et al., "Designs to improve polysilicon micromirror surface topology," in *Miniaturized systems with Micro-optics and Micromechanics II*, Motamedi et al, Eds., Proc. SPIE 3008, pp. 100-110, 1997	
	J6	BURNS et al., "Optical beam steering using surface micromachined gratings and optical phased arrays," in *Opt. Scanning Systems: Design and Appls.*, Proc. SPIE 3131, pp. 99-110, 1997.	
	K6	BURNS et al., "Investigation of the Maximum Optical Power Rating for a Micro-Electro-Mechanical Device, Proceedings, *Transducers '97*, pp. 335-338, Chicago, IL, June 16-19, 1997.	
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	M6	BURNS et al., "Optical power induced damage to microelectromechanical mirrors," *Sensors and Actuators A*, Vol. 70, pp. 6-14, 1998.	
	N6	BURNS et al., "Micro-electro-mechanical Variable Blaze Gratings," Proc., *IEEE 10th Annual Int. Workshop on MEMs: An Investigation of Microstructures, Sensors, Actuators, Machines, and Robots*, pp. 55-60, 1997.	

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	B7	FORD et al., "Micromechanical Fiber-Optic Attenuator with 3 μs Response," *Journal of Lightwave Technology*, Vol. 16, No. 9, pp. 1663-1670, September 1998.	
	C7	MIN et al., "Modeling, design, fabrication and measurement of a single layer polysilicon micromirror with initial curvature compensation," *Sensors and Actuators*, Vol. 78, pp. 8-17, 1999.	
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	E7	ROSSBERG, "Silicon micromachined infrared sensor with tunable wavelength selectivity for application in infrared spectroscopy," *Sensors and Actuators A*, Vol. 46-47, pp. 413-416, 1995.	
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